

Determination of thin film topography (Technion)

code: CHM-0676

Thin film metrology is extremely important in QA, inspection and process control procedures (e.g., in the semiconductors industry). Our three-beam interferometry compact system allows a low-cost, non-destructive, highly accurate measurement of thin film thickness and topography, with depths as thin as 2nm and without any limitation on substrate opacity.

Contact for more information:

Gabriel Shemer **≥** +972-4-8294851

T - Technion Technology Transfer Technion City, Senate Bldg., Haifa 32000, Israel Tel. 972-4-829-4851; 972-8325-375 Fax. 972-4-832-0845